

**IN THE CLAIMS:**

Amend the following claim:

Claim1 (currently amended): An electron microscope for observing a surface or inside of a semiconductor wafer or a mask for exposing a semiconductor pattern for faults and/or foreign objects, comprising

a function of loading measurement data of coordinates or sizes of faults or objects which were observed by another wafer or mask inspecting apparatus, moving ~~the~~ field of view of the electron microscope to ~~the~~ an area where said fault or object exists, and displaying the coordinates of said faults or objects which were obtained by another wafer or mask inspecting apparatus, ~~the~~ said faults or objects observed in said field of view of the electron microscope and its vicinity on a display,

a function of a pointing device having a switch which moves ~~the~~ said field of view of the electron microscope to a position which is pointed to by a pointer on said display, and

a function of ~~changing the display as said field of view moves~~ changing said field of view displayed on said display according to said moving of said field of view pointed to by said switch.

Claim 2 (original): An electron microscope in accordance with Claim 1, wherein the switch of said pointing device has a function to magnify or shrink the field of view of the electron microscope and its vicinity at any rate.

Claim 3 (original): An electron microscope in accordance with Claim 1, further comprising a function which magnifies or shrinks said field of view of the electron microscope and its vicinity as the field of view moves on a screen displaying said field of view of the electron microscope and its vicinity.

Claim 4 (original): An electron microscope in accordance with Claim 1, further comprising a function which moves and displays the center coordinates of the field of view and its vicinity as said field of view moves.

Claim 5 (original): An electron microscope in accordance with Claim 1, further comprising a function which displays shapes of faults on the screen displaying said field of view and a function which changes the display on the screen as the observing conditions of the electron microscope change.

Claim 6 (original): An electron microscope in accordance with Claim 1, further comprising a function which displays coordinates of faults or objects obtained by said another wafer or mask inspecting apparatus and distances of the field of view of the electron microscope, a function which stores said distance values, and a function which relatively moves the field of view of the electron microscope by said stored distances.

Claim 7 (original): An electron microscope in accordance with Claim 1, further comprising a function which displays an observed area and a non-observed area separately on the screen displaying said field of view and its vicinity, and a function which changes said display as the observing conditions of the electron microscope change.

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Add the following new claim:

Claim 8 (new): An electron microscope for observing a surface or inside of a semiconductor wafer or a mask for exposing a semiconductor pattern for faults and/or foreign objects, comprising:

A2  
a memory device for storing coordinate information of faults or objects which are obtained by observing said semiconductor wafer or said mask with another wafer or mask inspecting apparatus,

a control computer for controlling so as to move a field of view of said electron microscope based on said coordinate information, and

a display for displaying a position of said field of view of said electron microscope and its vicinity based on said coordinate information stored in said memory device,

a pointing device for pointing a part of said vicinity on said display, wherein

*A2 enclosed*  
said control computer controls said electron microscope so as to move said field of view of said electron microscope to a coordinate of said part pointed to by said pointing device, and

said display displays said semiconductor wafer or a mask observed in said field of view at said coordinate of said part pointed to by said pointing device.

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